AMENDMENTS TO THE CLAIMS

Docket No.: 27754/26717

The following Listing of Claims replaces all prior versions, and listings, of claims in the present application.

Listing of Claims

1-10. (Canceled).

11. (Currently amended) A method of forming a nozzle plate for droplet deposition apparatus, the nozzle plate defining a nozzle plate plane and comprising a plate having at least one nozzle plate layer and a plurality of nozzles, each nozzle extending through polymeric material located within a respective aperture within the nozzle plate, the method including the steps of:

defining a plurality of distinct bodies of polymeric material distributed over [[the]] \underline{a} nozzle plate plane, each said body having a periphery,

forming a plurality of nozzles, each nozzle extending through one of said distinct bodies of polymeric material distributed over the nozzle plate plane,

and subsequently to said step of defining a plurality of distinct bodies of polymeric material, forming at least one metal nozzle plate layer by electroforming around said peripheries of said bodies of polymeric material so that each of said distinct bodies of polymeric material is located within a corresponding one of a plurality of apertures within said metal nozzle plate layer and so that said peripheries of said bodies of polymeric material [[as to]] define at least in part the shapes of said apertures;

to provide a nozzle plate extending over said nozzle plate plane.

12-17 (Canceled).

18. (Currently amended). A method of forming a nozzle plate component for a droplet deposition apparatus, said method comprising the steps of:

forming a layer of first photoresist material on a substrate;

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subsequently selectively exposing and removing some of said first photoresist material

to define on the substrate an array of distinct bodies of said first photoresist material;

subsequent to said step of selectively exposing and removing first photoresist material,

forming a first plate of metal around said distinct bodies of said first photoresist material, so as

to form a metal nozzle plate having an array of apertures corresponding to said array of distinct

bodies of said first photoresist material, each aperture containing one of said bodies of said first

photoresist material; and

then forming a nozzle extending through each of said distinct bodies body of said first

photoresist material.

19. (Original). A method according to Claim 18, further comprising the step of depositing a

metallic layer on the substrate prior to forming of the layer of first photoresist material, said

first plate of metal being electroformed with said metallic layer serving as a seed layer.

20-21 (Canceled).

22. (Currently amended). A method according to claim 11, wherein each of said nozzles is

[[are]] formed by ablating each of said nozzles through one of said distinct bodies of polymeric

material located within a corresponding one of a plurality of apertures within said metal nozzle

plate layer.

23. (Currently amended). A method according to claim 18, wherein each of said nozzles is

[[are]] formed by ablating each of said nozzles through one of said distinct bodies of said first

photoresist material contained within an aperture in said first plate of metal.

24. (New) A method according to claim 11, further comprising the step of forming a further

layer in addition to said metal nozzle plate layer, said further layer comprising a plurality of

apertures aligned with said nozzles.

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25. (New) A method according to claim 18, wherein each of said nozzles has a diameter and

wherein said step of selectively exposing and removing said first photoresist material to define

on the substrate an array of distinct bodies of said first photoresist material comprises applying a

mask, said mask comprising an array of distinct mask features corresponding to said array of

distinct bodies, each of said mask features having a diameter greater than the diameter of the

nozzle of the corresponding body of first photoresist material.

26. (New) A method according to claim 18, further comprising the step of forming a further

layer in addition to said metal nozzle plate layer, said further layer comprising a plurality of

apertures aligned with said nozzles.

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